

光-電子相関顕微鏡システム

MirrorCLEM

Correlative light and electron microscopy system, MirrorCLEM

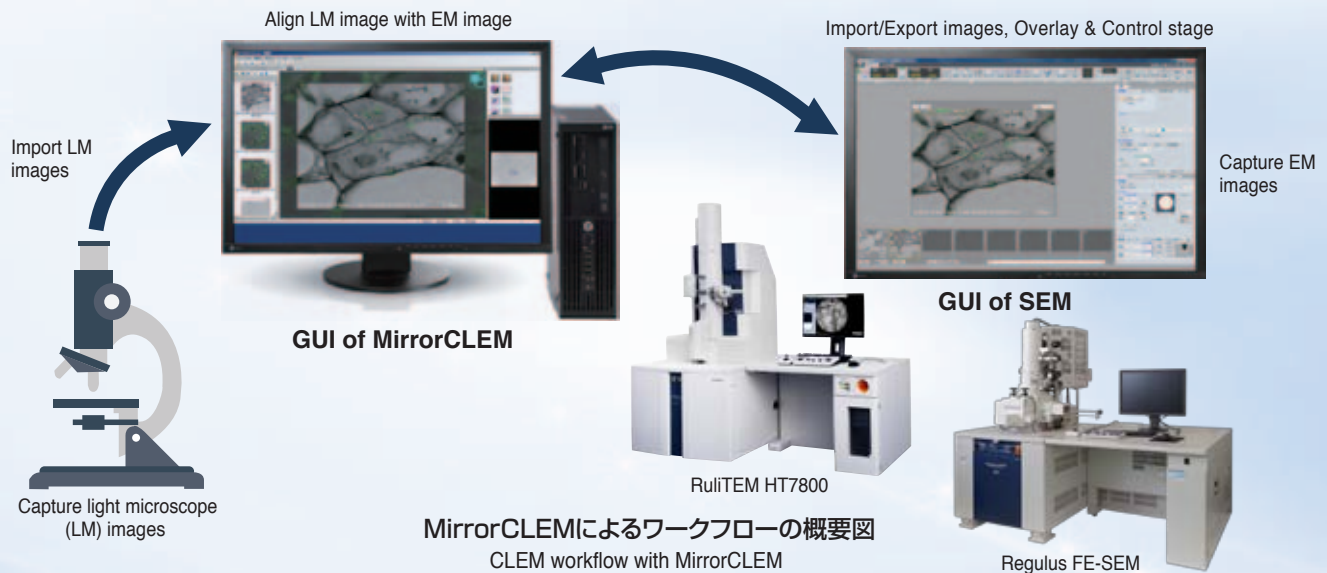
蛍光標識部位の超微形態のEM観察フローをサポート

Facilitating Electron Microscope (EM) observation of the fluorescent-labeled ultra-structure



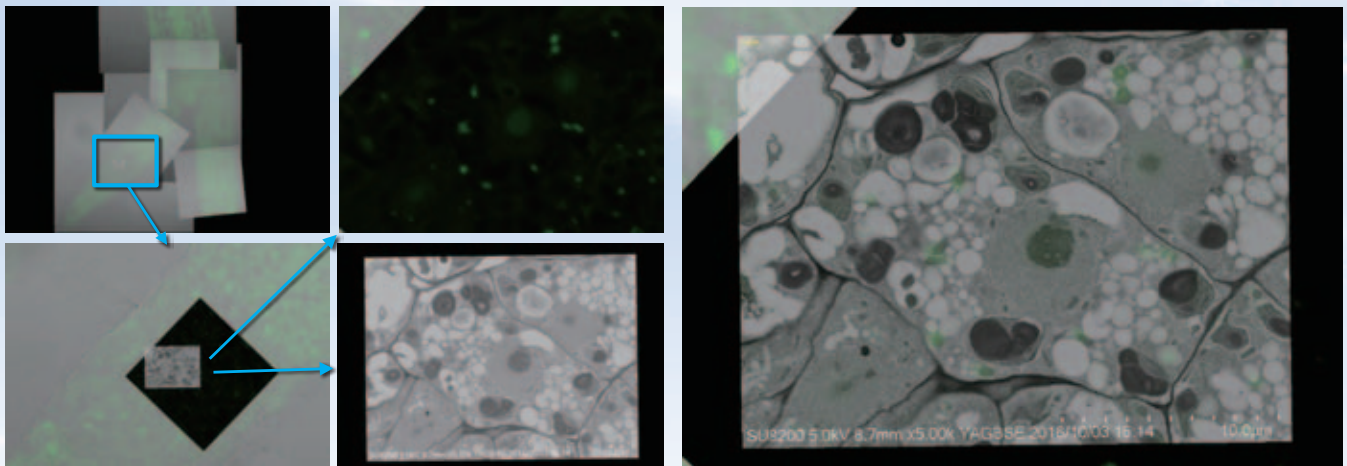
◎ 主な特長 Features

- 光学顕微鏡画像とSEM画像のアライメントにより、任意の蛍光顕微鏡観察位置にEMステージを外部制御
Once Light Microscope (LM) image is aligned with EM image, EM stage can be externally controlled to the area of interest on the fluorescent microscope image.
- 光顕像のオーバーレイをEM GUI上でリアルタイム表示し、相関観察を容易に実現
LM image is overlaid on EM GUI on a real-time basis for easy correlative imaging.



◎ 蛍光顕微鏡-SEM相関画像

Overlaid SEM and fluorescence image



Specimen : Cotyledon cells of *Arabidopsis thaliana*

Acc. Voltage : 5 kV, Mag. : x5 k, Signal : Peroxisome-GFP & DIC (Confocal laser scanning micrographs), YAG-BSE (SEM image)

Specimen courtesy by Kiminori Toyooka, RIKEN CSRS